

Light Scattering Tomography BMD Analyzer

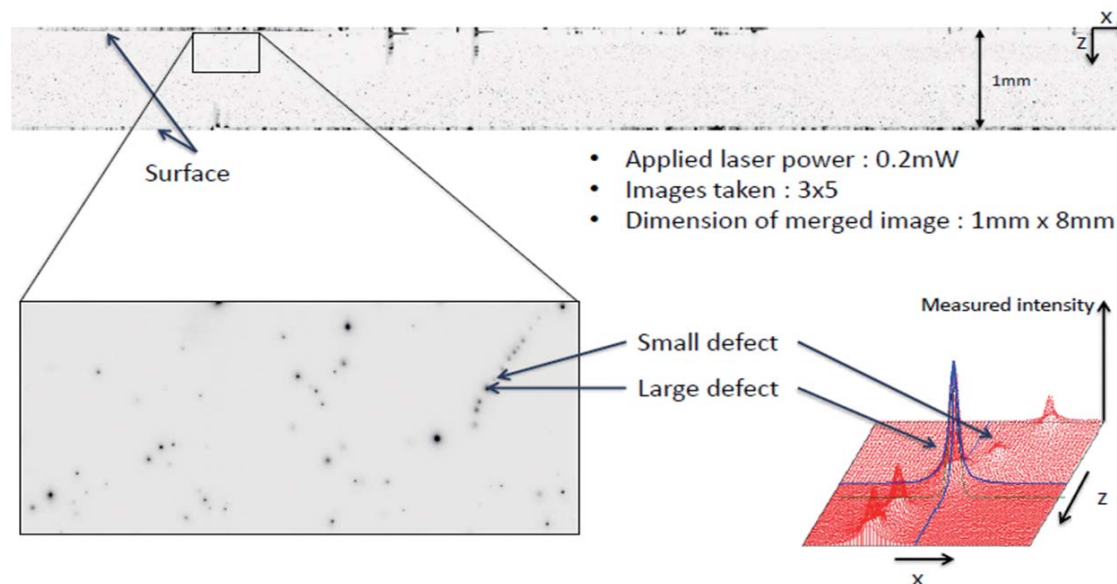
LST体微缺陷测试设备

LST is a powerful tool for monitoring bulk micro defect(BMD) profile of semiconductor samples. The BMD scatters the incident light which is recorded by a CCD camera near to the cleaved edge of the sample.

LST是检测半导体材料的体微缺陷有力工具，通过CCD相机，对入射光在样品边沿的散射进行扫描，获得体微缺陷分布信息。

Capability:

- Automatic objective changer
物镜自动调节
- Nano motion change
纳米级移动
- Improvement in size sensitivity and defect density
对缺陷浓度和尺寸更加灵敏
- Detection size: from 20nm to 15nm
测试尺寸：20nm到15nm
- Detection density: from $1e5$ - $2.5e10cm^{-3}$
缺陷浓度： $1e5$ - $2.5e10cm^{-3}$



LST measured about CdZnTe material